

ABSTRACT OF THE DISCLOSURE

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5 An exposure method and an exposure apparatus
are disclosed wherein one or more plural sample shot
processes are made to a substrate and an exposure
process is made to the substrate after completion of
the sample shot process or processes. The procedure
includes a first determining step for determining the
processing order in a first sample shot process, of
the plural sample shot processes, and a second
10 determining step for determining the processing order
in a second sample shot process to be made after the
first sample shot process, wherein, in at least one of
the first and second determining steps, the
determination is made under a condition that an
15 interval between a shot to be processed last in the
first sample shot process and a shot to be processed
first in the second sample shot process is shortened.

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